

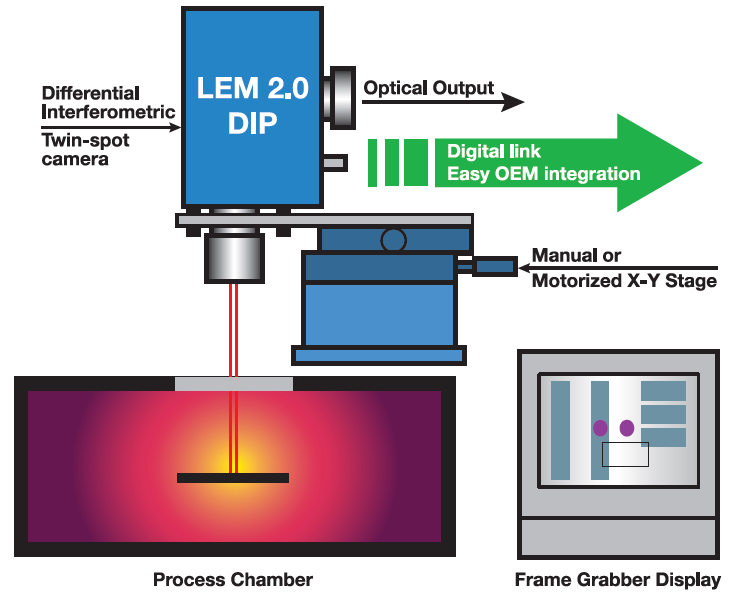
## LEM 2.0 DIP: Differential Interferometric Twin-Spot Camera *In-situ Deep ETCH EASY Monitoring*

### Unique NEW Sensor for Real-Time, High Resolution Monitoring of:

- Deep trench
- MEMS Etch applications
- Bosch process
- Failure analysis, ...

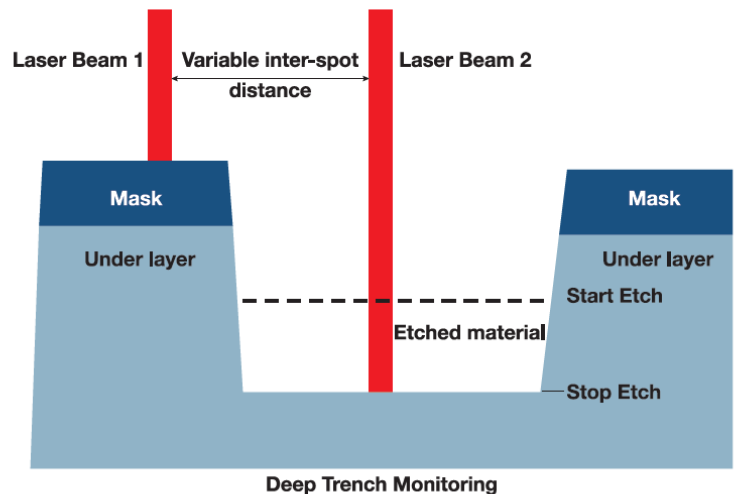
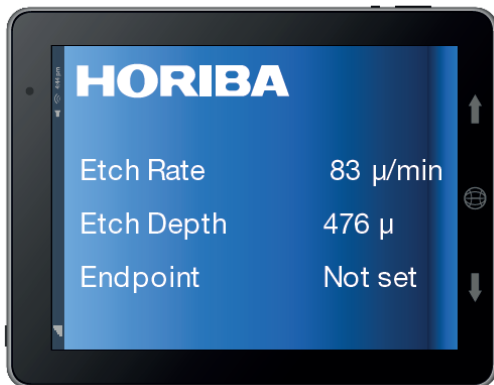
### SMART Digital Camera

- Digital OEM link, 24 V
- 2 laser spots at 635 nm
  - 1 spot on the mask
  - 1 spot on the trench
- LEM 2.0 algorithms & pattern recognition inside:  
**no external PC!**



### New SENSOR TECHNOLOGY for Etch Monitoring & Endpoint

- Phases measurement
- Ellipsometric accuracy
- From nm to hundreds of  $\mu$
- Immediate real-time display of



- Independent from PROCESS, even BOSCH: **No data fitting!**

# COMING SOON